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APPLICATION NO.	FI FI	LING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO	
10/728,135	/728,135 12/03/2003		Vencent Chang	JCLA12578	6798	
23900	7590	03/14/2006	•	EXA	EXAMINER	
J C PATEN			CHACKO DA	CHACKO DAVIS, DABORAH		
4 VENTURE, SUITE 250 IRVINE, CA 92618				ART UNIT	PAPER NUMBER	
,				1756		

DATE MAILED: 03/14/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)
	10/728,135	CHANG ET AL.
Office Action Summary	Examiner	Art Unit
	Daborah Chacko-Davis	1756
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address
A SHORTENED STATUTORY PERIOD FOR REPLY WHICHEVER IS LONGER, FROM THE MAILING DA - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION (6(a). In no event, however, may a reply be time till apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	N. nely filed the mailing date of this communication. D (35 U.S.C. § 133).
Status		
Responsive to communication(s) filed on <u>03 December</u> This action is FINAL . 2b)⊠ This Since this application is in condition for allowant closed in accordance with the practice under E	action is non-final. ice except for formal matters, pro	
Disposition of Claims	•	
4) ⊠ Claim(s) 1-13 is/are pending in the application. 4a) Of the above claim(s) is/are withdraw 5) □ Claim(s) is/are allowed. 6) ⊠ Claim(s) 1-13 is/are rejected. 7) □ Claim(s) is/are objected to. 8) □ Claim(s) are subject to restriction and/or		
Application Papers		,
9)☐ The specification is objected to by the Examiner	·.	
10)☐ The drawing(s) filed on is/are: a)☐ acce	epted or b) \square objected to by the E	xaminer.
Applicant may not request that any objection to the o		
Replacement drawing sheet(s) including the correction 11) The oath or declaration is objected to by the Example 11.		` ,
Priority under 35 U.S.C. § 119		
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priority application from the International Bureau * See the attached detailed Office action for a list of	have been received. have been received in Application ity documents have been received (PCT Rule 17.2(a)).	on No ed in this National Stage.
Attachment(s) 1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date	4) Interview Summary (Paper No(s)/Mail Da 5) Notice of Informal Pa 6) Other:	

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DETAILED ACTION

Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.
- 2. Claims 1-13, are rejected under 35 U.S.C. 102(e) as being anticipated by U.S. Patent No. 6,939,664 (Huang et al., herein after referred to as Huang).

Huang, in the abstract, in col 1, lines 65-67, in col 2, lines 1-4, in col 5, lines 11-19, in col 8, lines 56-67, in col 9, lines 35-50, in col 10, lines 22-67, in col 11, lines 1-24, discloses an immersion lithographic process comprising providing an imaging resist layer coated onto a first layer (resist composition planarizing layer) or a multilayer (wherein the intermixing between layers is inhibited, acid-generating layer included, CAR resist), performing exposure on the multilayered substrate forming exposed and unexposed portions of the imaging resist, wherein the exposed resist layer undergoes acid-catalyzed reaction (acid generated from the resist layer upon exposure) resulting in the solubilization of the exposed portion of the photoresist layer, developing the exposed imaging layer so as to remove the exposed portions of the imaging layer and the corresponding underlayers, wherein the remaining non-soluble portions of the top

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imaging layer function as a mask structure for further processing (claims 1, 7, and 11-12). Huang, in col 4, lines 55-67, in col 5, lines 1-10, in col 8, lines 25-40, discloses that the acid is generated in the exposed portions of the photoresist (positive resist compositions) alters the polarity of the exposed portion of the photoresist (acid-catalyzed reactions in the exposed portions of the photoresist) and correspondingly alters the polarity of the imaging layer (protective layer), resulting in soluble (hydrophilic) and insoluble (hydrophobic) portions in the imaging and underlying layers, wherein the soluble portions are removed in the developing step (claims (claims 2-4, 8). Huang, in col 11, lines 1-10, discloses that the exposed imaging layer is baked to promote acid-catalyzing reactions (solubilizing step) prior to the development (claim 5, 9). Huang in col 14, lines 49-53, discloses forming the photoresist layer on an ARC (anti-reflection layer) coated wafer (claims 6, 10, and 13).

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Conclusion

3. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Daborah Chacko-Davis whose telephone number is (571) 272-1380. The examiner can normally be reached on M-F 9:30 - 6:00. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Mark F Huff can be reached on (571) 272-1385. The fax phone number for the organization where this application or proceeding is assigned is (571) 273-8300. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published

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applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

dcd

March 7, 2006.

JOHN A. MCPHERSON PRIMARY EXAMINER Page 4